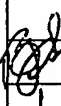

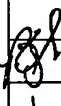





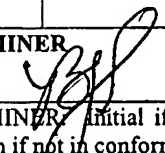
PTO-1449		Application No.		Applicant(s)	
Information Disclosure Citation in an Application		Docket Number 004578.1148		Dipankar (nmi) Chandra, et al.	
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EXAMINER Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.		

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